

## ***Interactive comment on “Vapor wall deposition in Teflon chambers” by X. Zhang et al.***

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The comment was uploaded in the form of a supplement:

<http://www.atmos-chem-phys-discuss.net/14/C12000/2015/acpd-14-C12000-2015-supplement.pdf>

Interactive comment on Atmos. Chem. Phys. Discuss., 14, 26765, 2014.

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